



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

	In re F	Patent Application of:)		
	Shunp	ei YAMAZAKI)	Group Art Unit: 2814	
	Serial	No. 09/620,968)	Examiner: Nathan W. Ha	
	Filed:	July 20, 2000)	Confirmation No. 4214	
	For:	METHOD OF FORMING INSULATING FILM CAPACITANCES, AND SEMICONDUCTOR DEVICE	is,)	Date: January 30, 2006	
			CERTIFICATE OF MAILING OR TRANSMISSION [37 CFR 1.8(a)]			
do			Class Ma Commiss 1450, or t	I hereby certify that this correspondence is being deposite with the United States Postal Service with sufficient postage for Fir class Mail in an envelope addressed to: Mail Stop Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 2231: 450, or being facsimile transmitted to the USPTO at, canuary 30, 2006.		
			Signature:			
			N1			

REQUEST FOR RECONSIDERATION

Mail Stop AF Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the final Office Action mailed October 28, 2005, please consider Applicant's remarks in connection with the above identified application as follows.